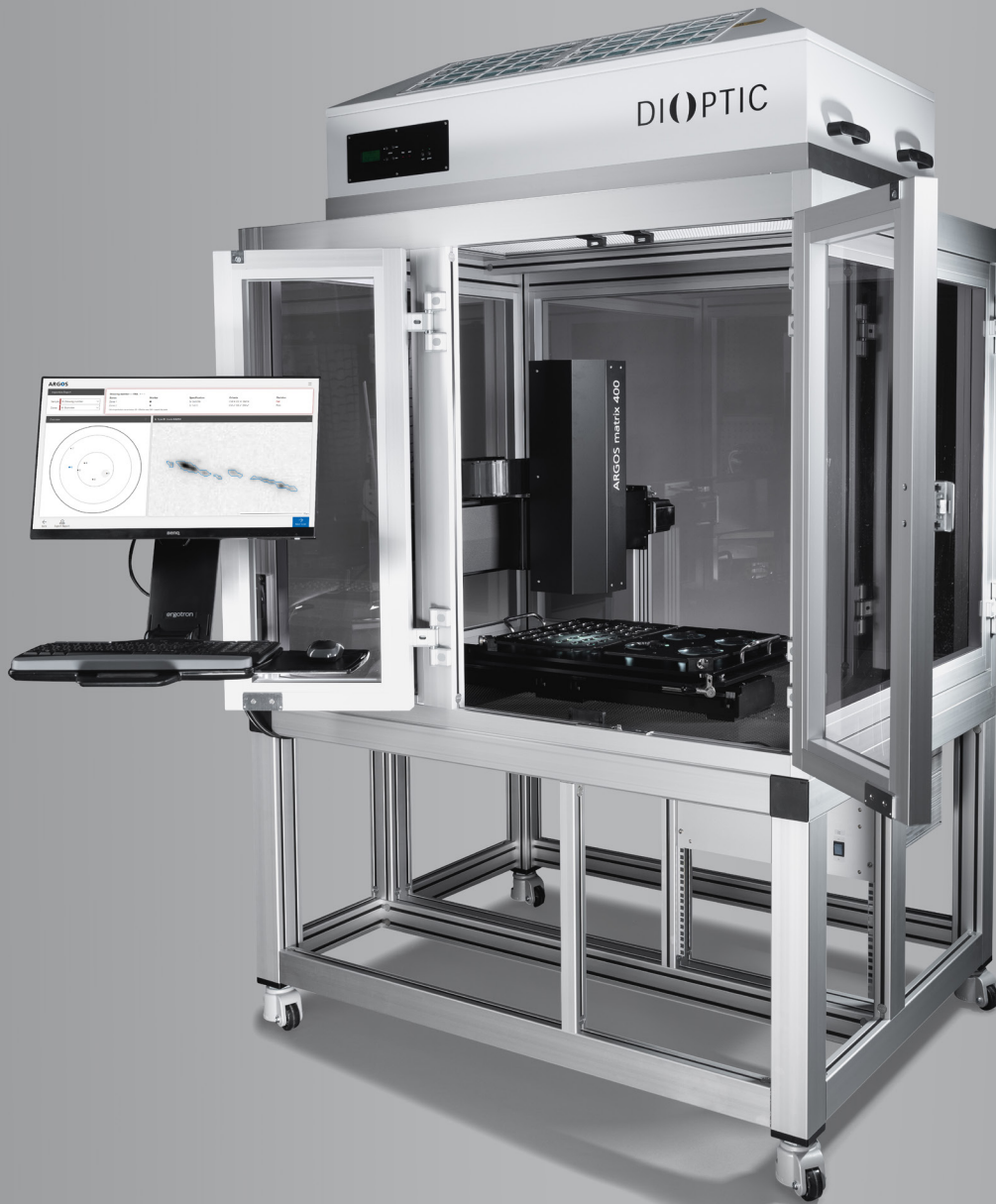


# ARGOS matrix 400

automated scratch/dig inspection

**DI OPTIC**  
creating optical solutions



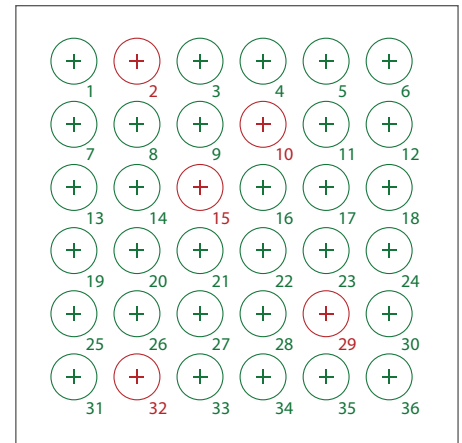
- FULLY AUTOMATED SURFACE INSPECTION
- VERSATILE FROM MICRO-OPTICS TO WAFERS
- OBJECTIVE AND REPRODUCIBLE



Automated stitching of large parts



Serial inspection of many parts on a tray



Clear pass/fail decision and detailed reports

## BENEFITS

**Large flexibility:** any shape from aspheric micro lenses to 12" wafers can be inspected.

**Automated serial inspection without user interaction** reduces cost and improves process quality.

**Objective test results with clear decisions and detailed information** on relevant defects and statistics.

## FUNCTIONALITY

ARGOS matrix 400 is equipped with a high-resolution camera and a switchable dark-field illumination. A precision 400x400 mm stage allows inspection of either large numbers of parts or a single large surface - flat or curved.

PDF test reports with clear decision and detailed information are automatically created. The ARGOS matrix 400 is equipped with an integrated filter fan unit that ensures a laminar air flow in the system.

## SPECIFICATIONS

ARGOS measurement head	ARGOS matrix S	ARGOS matrix M	ARGOS matrix L
Smallest ISO 10110-7 size grade	0.004 (digs), 0.0025 (scratches)	0.0063 (digs), 0.004 (scratches)	0.01 (digs), 0.0063 (scratches)
Smallest visible defects*	< 1 µm	< 2 µm	< 3 µm
Reproducibility of the size measurement*	< 1.5 µm	< 3 µm	< 4.5 µm
Inspection example*: 8" wafer	12 min	4 min	2 min
Inspection example*: Lens, D=30mm, curvature R=30mm	4 min	2 min	15s
Maximum inspection area / System size (LxWxH)	600x400 mm / 1510x1085x2322 mm		
Surface materials	Polished, uncoated or coated surfaces with optical quality, e.g. glass, semiconductors, metals, plastics, crystals, other surface types on request.		

\*for details see technical specification document